



1775

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of **Steinberg**

Application No. 10076858

Attorney Docket No. Shipley 03-19; DN: 51969 (Act - 183/184)

Filed: February 14, 2002

For: MICROMACHINED STRUCTURES
MADE BY COMBINED WET AND
DRY ETCHING

Examiner: Stephen J. Stein

Group Art Unit: 1775

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TC 1700

CERTIFICATE OF MAILING UNDER 37 C.F.R § 1.8(a)

I hereby certify that this Correspondence is being deposited on the date identified below with the United States Postal Service as first-class mail in an envelope properly addressed to Commissioner for Patents, Alexandria, VA 22313-1450.

11-12-2003

Date of Certificate

Cristin Donahue
Cristin Donahue

Commissioner for Patents
Alexandria, VA 22313-1450

**INFORMATION DISCLOSURE STATEMENT
UNDER 37 C.F.R. § 1.97**

In compliance with the duty of disclosure set forth in 37 C.F.R. § 1.56, Applicants are submitting herewith a Form PTO-1449 and a copy of the references listed thereon. This Information Disclosure Statement is being filed more than three months after the filing date of the application. However, Applicants have not yet received an action on the merits of the application. Accordingly, Applicants believe that no fee is required pursuant to 37 C.F.R. § 1.97 (b) (3). In the event a fee is required, the Commissioner is authorized to charge the required fees to deposit account no. 04-1406. A duplicate copy of this sheet is included for fee processing, if necessary.

Applicants respectfully request full and proper consideration of the listed

information during examination of the application, and that the listed information be printed on any patent that issues therefrom.

Respectfully submitted,

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By



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Enclosures - Form PTO-1449

Copies of references listed on PTO - 1449



INFORMATION DISCLOSURE STATEMENT

Complete if known

Application Number: 10076858

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Filing Date: February 14, 2002

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First Named Inventor: Steinberg

TC 1700

Group Art Unit: 1775

Examiner Name: Stephen J. Stein

SHEET 1 OF 1

Attorney Docket Number: Shipley 03-19; DN: 51969 (Act - 183/184)

UNITED STATES PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO.	PATENT NUMBER	ISSUE DATE MM-DD-YYYY	FIRST NAMED INVENTOR

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO.	DOCUMENT NUMBER	COUNTRY OR REGION	DATE OF PUBLICATION MM-DD-YYYY	FIRST NAMED INVENTOR OR APPLICANT

OTHER PRIOR ART - NON-PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO.	Include name of the author (in Capital Letters), title of the article (when appropriate), title of the item(book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published
		J. G. Fleming, "Combining the best of bulk and surface micromachining using Si {111} substrates." SPIE Vol. 3511, September 1998, pp. 162-168.
		J. Brugger, et al., "Self-aligned 3D shadow mask technique for patterning deeply recessed surfaces of micro-electro-mechanical systems devices." Sensors and Actuators 76 (1999) pp. 329-334.

EXAMINER'S SIGNATURE		DATE CONSIDERED	
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP § 609. Draw a line through citation if citation not in conformance and reference not considered. Include a copy of this form with next communication to applicant.